

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: S. KATO, et al.

Application No.: 10/060,204

Filed: SEPTEMBER 24, 2002

For: VACUUM PROCESSING APPARATUS WITH WAFERS,  
SUBSTRATES AND/OR SEMICONDUCTORS

Group AU: 3749

Examiner: Stephen Michael Gravini

Confirm. No.: 7506

**AMENDMENT PAPER****Mail Stop: AMEND – FEE**

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

July 19, 2007

SIR:

In response to the Office Action mailed March 19, 2007, the period for response having been extended for one (1) month by the attached petition for extension of time, please amend the above-identified application as follows:

**IN THE SPECIFICATION:**

Please delete the paragraph at column 1, lines 3-20, as amended in the Supplementing Amendment Paper filed September 24, 2002, and substitute therefor the following new paragraph:

-- This application is a Divisional application of application Ser.

No. 09/461,432, filed Dec.16, 1999 now U.S. Pat. No. 6,330,755, which is a  
Continuation application of application Ser. No. 09/177,495, filed Oct. 23, 1998 now  
U.S. Pat. No. 6,012,235, which is a Continuation application of application Ser.  
No. 09/061,062, filed Apr.16, 1998 now U.S. Pat. No. 5,950,330, which is a  
Continuation application of application Ser. No. 08/882,731, filed Jun. 26, 1997 now